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IN THE CLAIMS:

Please substitute the following amended claims for the corresponding original claims. A marked copy of the claim amendments is attached hereto.

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1. (amended seven times) A process chamber for processing a substrate in a process gas and reducing emissions of hazardous gas to the environment, the process chamber comprising:

- (a) a support capable of supporting the substrate;
- (b) a gas distributor capable of introducing process gas into the process chamber;
- (c) a gas activator capable of activating the process gas to perform a process in the process chamber thereby forming effluent containing hazardous gas;
- (d) an exhaust tube through which the effluent may be flowed, the exhaust tube comprising sapphire and the exhaust tube being adapted to provide a non-circuitous and non-turbulent flow of effluent therethrough by being substantially absent projections or recesses (i) that alter the flow direction of the effluent to provide a circuitous flow of effluent through the exhaust tube, and (ii) that cause turbulence in the flow of the effluent through the exhaust tube; and
- (e) a microwave energy applicator to couple microwaves to the effluent flowing through the exhaust tube to reduce the hazardous gas content of the effluent.

7. (amended four times) The process chamber of claim 1 wherein the [exhaust tube] sapphire comprises monocrystalline sapphire.